

Automatic Slide Transfer

The Automatic Slide Transfer uses a motorized moving platform to transfer wafers thereby eliminating operator-induced errors. Operation consists of placing the cassettes on the platform and pressing the start button. Interlock sensors detect cassette presence to ensure wafer transfer safety. Wafers are transferred by edge-only contact using clean, low particle materials. A wide-pusher option is available for flatted wafers to maintain alignment if flats are generally in direction of pusher. Models are available for all wafer sizes except 300mm.